

WHAT IS CLAIMED IS:

1. A substrate holding device for holding a substrate, comprising:
a substrate stage for supporting the substrate;
a stage drive mechanism for causing the substrate stage to move;
a positioning pin for positioning the substrate on the substrate stage;
a positioning pin stage,
first urging members each urging the positioning pin; and
a stopper member capable of applying a force against the first urging member to the positioning pin,
wherein the positioning pin is configured to move together with the substrate stage by the stage drive mechanism, and the positioning pin moving together with the substrate stage allows the substrate to be positioned on the substrate stage, and
wherein the positioning pin is fixed to the positioning pin stage, and
the positioning pin stage is configured to be capable of engaging with and disengaging from the substrate stage.
2. The substrate holding device according to claim 1, further comprising:
a base member whose position is fixed,
wherein the stopper member is fixed to the base member.
3. The substrate holding device according to claim 1, wherein
the positioning pin stage is configured to be movable between (1) an engagement position at which the positioning pin stage engages with the substrate stage and (2) a disengagement position at which the positioning pin stage disengages from the substrate

stage, the engagement position and the disengagement position being separate from each other in a direction perpendicular to a top surface of the substrate stage.

4. The substrate holding device according to claim 3, wherein
the positioning pin includes a substrate support portion, and
the positioning pin is configured to be capable of supporting the substrate by the substrate support portion when the positioning pin stage is at the disengagement position.

5. The substrate holding device according to claim 1, further comprising:
a base member whose position is fixed, wherein the stopper member is fixed to the base member;

the positioning pin stage is connected to the base member through a second urging member, and the second urging member is configured to urge the positioning pin stage in a direction opposite to a direction in which the positioning pin stage moves together with the substrate stage.

6. The substrate holding device according to claim 1, wherein
the positioning pin is urged by the first urging member in a central direction of the substrate.

7. The substrate holding device according to claim 1, wherein
the number of the positioning pin is three or more.

8. The substrate holding device according to claim 7, wherein
the number of the positioning pin is six or more.

9. The substrate holding device according to claim 1, wherein
the substrate stage has a circular top surface for supporting a circular substrate.

10. The substrate holding device according to claim 9, wherein
the stage drive mechanism has a motor for rotating the substrate stage, and
the positioning pin is configured to position the substrate so that a center of the

substrate coincides with a rotation center of the substrate stage.

11. A substrate processing apparatus, comprising:
the substrate holding device according to claim 1,
wherein the substrate processing apparatus is configured to perform processing on
a substrate held by the substrate holding device.
12. The substrate processing apparatus according to claim 11, comprising:
a partial polisher partially polishing the substrate held by the substrate holding
device.